

10/562158

Docket No.: 4684-030

JC10 Rec'd PCT/PTO 23 DEC 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Confirmation No.

Kang-Ho AHN

Group Art Unit: -----

U.S. Patent Application No.: -----

Filed: *herewith*

For: APPARATUS FOR CONTROLLING FLOW RATE OF GASES USED IN
SEMICONDUCTOR DEVICE BY DIFFERENTIAL PRESSURE

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Preliminary to examination of the above-referenced application, please amend the application as follows: